

XEI SCIENTIFIC

Evactron® RF Plasma Cleaning Systems for Electron Microscopes

CE Declaration of Conformity

Manufacturer: XEI Scientific
1735 East Bayshore Rd. Ste. 29A, Redwood City, CA 94063
(650) 369-0133, FAX (650) 363-1659
www.Evactron.com, Rvane@Evactron.com

Model: Evactron® Model 10 and Model C Anti-Contaminator

Type of Equipment: RF Plasma Cleaning System for vacuum systems

Application of Council Directives(s): 73/23/EEC as last amended by EC Directive 93/68/EEC (Low Voltage Directive) and Annex I of 98/37/EC (Machinery Directive)

Testing Provider and Certification body: TUV Rheinland of North America, San Francisco Office

Tests: Confirmation of conformity to the Low Voltage and Machinery Directive: IEC 61010-1:2001 & Annex I of 98/37/EC (Machinery Directive)
TUV: file number 30372945.001 and .002

Certificate of Conformity to Electromagnetic Compatibility
EC Directive 89/336/EEC as last amended by EC Directive 93/68/EEC
Tested acc. to: EN 61326: 1997+A1+A2
TUV Report No. 30362933 001
Registration No. AE 72032483 0001

I, the Undersigned, hereby declare that the equipment above conforms to the above Directives and Standards, when installed in accordance with the manufacturers specifications.

Place of Issue: Redwood City, CA _____

Date of Issue: April 7, 2004

Ronald Vane - President